

**AMENDMENTS TO THE CLAIMS:**

This listing of claims will replace all prior versions, and listings, of claims in the application.

**Listing of Claims:**

1-15. (Cancelled)

16. (Currently Amended) A process for forming an insulating film on the surface of a substrate for an electronic device, comprising the steps of: cleaning the substrate with plasma based on a ~~first process~~ cleaning gas comprising at least a rare gas; and

oxidizing the substrate with plasma based on a ~~second process~~ an oxidizing gas comprising at least a rare gas and oxygen, to thereby form an oxide film thereon;

nitriding the oxide film with plasma based on a nitriding gas comprising a rare gas and nitrogen after the oxidizing; and

treating the oxide film with plasma based on a treating gas comprising hydrogen gas after the nitriding;

wherein the cleaning and oxidizing steps are conducted under the same operation principle; and

the cleaning and oxidizing steps are conducted in the same vessel without exposure of the substrate to air.

2 17. (Currently Amended) A process for forming an insulating film according to claim 16, wherein the ~~first process~~ cleaning gas comprises hydrogen gas.

3 18. (Currently Amended) A process for forming an insulating film according to claim 16, wherein the ~~first step~~ cleaning is conducted at a pressure of 7-133 Pa.

4 19. (Currently Amended) A process for forming an insulating film according to claim 16, wherein the ~~first and second steps~~ cleaning and oxidizing are conducted in the same processing chamber or in different processing chambers under the same operation principle.

20-22. (Canceled)

5 23. (Currently Amended) A process for forming an insulating film according to claim [[21]] 16, which further comprises a step to be conducted after the fourth step, of forming a High-k film after the treating.

24. (Canceled)

2 25. (Currently Amended) A process for forming an insulating film on the surface of a substrate for electronic device, comprising the steps of:

cleaning the substrate with plasma based on a ~~first process~~ cleaning gas comprising ~~at least~~ a rare gas; and

nitriding the substrate with plasma based on a ~~second process~~ nitriding gas comprising ~~at least~~ a rare gas and nitrogen, to thereby form a nitride film thereon;

oxidizing the nitride film with plasma based on an oxidizing gas comprising a rare gas and oxygen after the nitriding; and

treating the nitride film with plasma based on a treating gas comprising hydrogen gas after the oxidizing;

wherein cleaning and nitriding steps are conducted under the same operation principle; and

the cleaning and nitriding steps are conducted in the same vessel without exposure of the substrate to air.

26. (Currently Amended) A process for forming an insulating film according to claim 25, wherein the ~~first process~~ cleaning gas comprises hydrogen gas.

27. (Currently Amended) A process for forming an insulating film according to claim 25, wherein the ~~first step~~ cleaning is conducted at a pressure of 7-133 Pa.

15 28. (Currently Amended) A process for forming an insulating film according to claim 25, wherein the ~~first and second steps~~ cleaning and nitriding are conducted in the same processing chamber or in different processing chambers under the same operation principle.

29-31. (Canceled)

16 32. (Currently Amended) A process for forming an insulating film according to claim 31, which further comprises ~~a step to be conducted after the fourth step~~, of forming a High-k film after the treating.

33-41. (Canceled)

16 42. (Currently Amended) A process for forming an insulating film according to claim [[20]] 16, wherein the ~~third step~~ nitriding and/or treating is conducted in a processing chamber that is the same as or different from the processing chamber wherein the ~~first and second steps~~ cleaning and oxidizing are conducted.

43-44. (Canceled)

18 45. (Currently Amended) A process for forming an insulating film according to claim [[29]] 25, wherein the ~~third step~~ oxidizing and/or treating is

conducted in a processing chamber that is the same as or different from the processing chamber wherein the ~~first and second steps~~ cleaning and nitriding are conducted.

46-53. (Canceled)

~~X~~ 54. (Currently Amended) A process for forming an insulating film according to claim 16, wherein the plasma is generated using microwave irradiation by using a plane antenna member having a plurality of slots.

~~2P~~ 55. (Currently Amended) A process for forming an insulating film according to claim 25, wherein the plasma is generated using microwave irradiation by using a plane antenna member having a plurality of slots.

~~8~~ 56. (Currently Amended) A process for forming an insulating film according to claim 23, wherein the High-k film comprises ~~at least~~ one material selected from the group consisting of Al<sub>2</sub>O<sub>3</sub>, ZrO<sub>2</sub>, HfO<sub>2</sub>, Ta<sub>2</sub>O<sub>5</sub>, ZrSiO, HfSiO and ZrAlO.

57. (Canceled)

~~1A~~ 58. (Currently Amended) A process for forming an insulating film according to claim 32, wherein the High-k film comprises ~~at least~~ one material

selected from the group consisting of Al<sub>2</sub>O<sub>3</sub>, ZrO<sub>2</sub>, HfO<sub>2</sub>, Ta<sub>2</sub>O<sub>5</sub>, ZrSiO, HfSiO and ZrAlO.

59-63. (Canceled)

9 64. (Previously Presented) A process for forming an insulating film according to claim 16 wherein the insulating film is a gate insulator.

10 65. (Previously Presented) A process for forming an insulating film according to claim 25 wherein the insulating film is a gate insulator.

66. (Withdrawn) A semiconductor device manufacturing system for conducting a process for forming an insulating film on the surface of a substrate for an electronic device, the system comprising:

- a cassette containing a substrate;
- a transportation chamber for transporting the substrate;
- a first arm for disposing the substrate in the transportation chamber;
- a plurality of plasma processing units for conducting treatments on the substrate, which is to be introduced into the plasma processing unit via the arm connected to the transportation chamber;
- a load lock unit for conducting the communication and isolation between the cassette and the transportation chamber via a second arm;

wherein the plasma processing unit conducts a process comprising a first step of cleaning the substrate with plasma based on a first process gas comprising at least a rare gas; and a second step of oxidizing or nitriding the substrate with plasma based on a second process gas, to thereby form an oxide or nitride film thereon; wherein the first and second steps are conducted under the same operation principle.

67. (Withdrawn) A semiconductor device manufacturing system according to claim 66, which further comprises a heating unit for operating heating treatment.

68. (Withdrawn) A semiconductor device manufacturing system according to claim 66, which further comprises a heating reaction furnace for conducting heating treatment on the substrate.

69. (Withdrawn) A semiconductor device manufacturing system according to claim 66, wherein any of the plasma processing unit conducts a fourth step of treating the insulating film with plasma based on a fourth process gas comprising hydrogen gas.

70. (Withdrawn) A semiconductor device manufacturing system according to claim 66, wherein the heating unit conducts a step of forming a High-k film.

10/1. (Previously Presented) A process for forming an insulating film according to claim 16 wherein the substrate is subjected to wet cleaning prior to the plasma cleaning.

11/2. (Previously Presented) A process for forming an insulating film according to claim 25 wherein the substrate is subjected to wet cleaning prior to the plasma cleaning.

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